

# IN THE SPECIFICATION

Please replace the paragraph beginning on page 7, at line 3 with the following:

The rotational driving apparatus ~~[[34]]~~ (not shown) is further provided in the system to rotate the chuck plate 20 around the center position where the wafer W is normally placed.

Please replace the paragraph beginning on page 10, at line 16 with the following:

In addition, at least one or more optical sensor ~~3262~~ is provided above the chuck plate ~~2046~~ in order to illuminate the edge portion of wafer W with a probe light beam, as shown in Fig. 7, by which wafer position and wafer position state can be detected based on the degree of the reflected beam or refracted beam.

Please replace the paragraph beginning on page 10, at line 20 with the following:

A controller (not shown) is provided outside the chamber 42 to selectively output a door open/close control signal, a rotational control signal and a fluid flow control signal to the door means ~~38~~(not shown) and rotational driving apparatus ~~[[34]]60~~ and valve ~~2864~~, respectively. The controller serves to compare the detected signal outputted from the sensor ~~3056~~ and the optical sensor ~~3262~~ with the reference values to determine whether the wafer W is normally placed on the chuck plate and output the resultant information to an output device (not shown).